



ASMIN.T.055AUS

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Timmermans et al.
Appl. No. : 10/690,215
Filed : October 20, 2003
For : METHOD FOR THE
DEPOSITION OF SILICON
NITRIDE FILMS (As amended
herein)
Examiner : Unknown
Group Art Unit : Unknown

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

January 20, 2004

(Date)

Adeel S. Akhtar, Reg. No. 41,394

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to examination on the merits in the above-referenced application, please amend the application as indicated below:

Amendments to the Specification begin on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.